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# In<sub>0.69</sub>Al<sub>0.31</sub>As<sub>0.41</sub>Sb<sub>0.59</sub>/In<sub>0.27</sub>Ga<sub>0.73</sub>Sb double-heterojunction bipolar transistors with InAs<sub>0.66</sub>Sb<sub>0.34</sub> contact layers

J.G. Champlain, R. Magno, R. Bass, D. Park and J.B. Boos

Presented are the first DC and RF results for a double heterojunction bipolar transistor, at a 6.2 Å lattice constant, incorporating InAs<sub>0.66</sub>Sb<sub>0.34</sub>. These devices show excellent performance with a high collector current density of  $1.9 \times 10^5 \text{ A/cm}^2$ , high breakdown voltage over 2.5 V, high short-circuit current gain cutoff frequency of 59 GHz, and maximum frequency of oscillation of 34 GHz.

**Introduction:** The 6.1 Å materials, and by extension the 6.2 Å materials, have shown great promise for low-power, high-speed performance owing to a large range of available bandgaps, band offsets, and high electron and hole mobilities [1–4]. Diodes fabricated in the 6.2 Å material system have shown high current densities at very low voltages, leading to devices that consume half the power of similar InP-based devices and a fifth the power of similar GaAs-based devices. In this Letter, the first In<sub>0.69</sub>Al<sub>0.31</sub>As<sub>0.41</sub>Sb<sub>0.59</sub>/In<sub>0.27</sub>Ga<sub>0.73</sub>Sb double-heterojunction bipolar transistors (HBTs) incorporating InAs<sub>0.66</sub>Sb<sub>0.34</sub> for use as the emitter contact and sub-collector layers is presented. Use of InAs<sub>0.66</sub>Sb<sub>0.34</sub> results in a significant improvement in performance over the first reported HBTs in this material system [5]. These devices show excellent DC and RF performance with the highest measured short-circuit current gain cutoff frequency ( $f_T$ ) for an HBT fabricated in this material system.

**Growth and fabrication:** The HBTs were grown by solid-source molecular beam epitaxy (MBE) using As<sub>2</sub> and Sb<sub>2</sub> from valved cracking sources. From substrate to surface, the growth consisted of a semi-insulating (SI) GaAs substrate; a buffer of 3000 Å GaAs, 12 Å AlSb, 5000 Å Al<sub>0.65</sub>Ga<sub>0.35</sub>Sb, and 1 μm of In<sub>0.21</sub>Ga<sub>0.19</sub>Al<sub>0.60</sub>Sb; a 5000 Å n<sup>+</sup> (Te: 4 × 10<sup>18</sup> cm<sup>-3</sup>) InAs<sub>0.66</sub>Sb<sub>0.34</sub> sub-collector; a 1950 Å n In<sub>0.69</sub>Al<sub>0.31</sub>As<sub>0.41</sub>Sb<sub>0.59</sub> collector consisting of a 400 Å doping grade (Te: 4 × 10<sup>18</sup> ~ 5 × 10<sup>16</sup> cm<sup>-3</sup>) adjacent to the subcollector, a 1500 Å low doped (Te: 5 × 10<sup>16</sup> cm<sup>-3</sup>) region, and a 50 Å UID layer adjacent to the base; a 1000 Å p<sup>+</sup> (Be: 3 × 10<sup>19</sup> cm<sup>-3</sup>) In<sub>0.27</sub>Ga<sub>0.73</sub>Sb base; a n In<sub>0.69</sub>Al<sub>0.31</sub>As<sub>0.41</sub>Sb<sub>0.59</sub> emitter consisting of a 500 Å moderately doped (Te: 2 × 10<sup>17</sup> cm<sup>-3</sup>) layer adjacent to the base, a 90 Å doping grade (Te: 2 × 10<sup>17</sup> ~ 6.7 × 10<sup>18</sup> cm<sup>-3</sup>), and a 210 Å highly doped (Te: 6.7 × 10<sup>18</sup> cm<sup>-3</sup>) layer adjacent to the emitter contact layer; and a 100 Å n<sup>+</sup> (Te: 9.6 × 10<sup>18</sup> cm<sup>-3</sup>) InAs<sub>0.66</sub>Sb<sub>0.34</sub> emitter contact. InAs<sub>0.66</sub>Sb<sub>0.34</sub> has been shown to have superb electron transport properties and offers extremely low contact resistance when used for n-type ohmic contacts, making it an excellent choice for the n-type emitter contact and sub-collector layers [6]. Alternatively, In<sub>0.27</sub>Ga<sub>0.73</sub>Sb has been shown to have excellent hole transport properties and results in extremely low resistance, p-type contacts, making it an ideal choice for the p-type base layer [7].

The HBTs were fabricated using standard processing and e-beam lithography techniques. The emitter and collector n-type contacts consisted of an unannealed Ti:Pt:Au (100:50:2500 Å) stack [6]. The base p-type contact consisted of an unannealed Pd:Pt:Au (100:50:2500 Å) stack [7]. The emitter mesa was defined using a tartaric-based wet etch, with the base mesa defined by SiCl<sub>4</sub>-based ICP RIE. The tartaric-based etch used for the emitter mesa etch is non-selective, requiring a thicker base layer ( $t_{base} = 1000$  Å) to guarantee a good yield. After device isolation by a wet etch, co-planar ground-signal-ground waveguides were deposited onto the SI GaAs substrate with airbridges to the relevant HBT contacts.

**Measurements, results, analysis:** The Gummel plot and common-emitter collector characteristics for an HBT with a 2 × 10 μm<sup>2</sup> emitter contact area are shown in Figs. 1 and 2, respectively. The area of the base-emitter junction, measured by scanning electron microscopy (SEM), is approximately 1.4 × 9.4 μm<sup>2</sup>, owing to undercutting during the emitter wet etch. The device shows excellent base and collector idealities of  $\eta_B = 1.5$  and  $\eta_C = 1.0$ , respectively. The improvement of the base ideality ( $\eta_B$ ) and high base-emitter voltage before the diodes become resistively limited, as compared to previous results [4, 5, 8], suggest that the inclusion of InAs<sub>0.66</sub>Sb<sub>0.34</sub> for the emitter contact and sub-collector layers has reduced the relative series resistance seen by

each junction, improving the overall performance of the device. The low current gain,  $\beta = I_C/I_B = 2 - 3$ , is believed to be due to Be diffusion into the emitter, removing the efficacy of the base-emitter heterojunction, as similar device structures have yielded current gains as high as 17 ~ 20 [4, 5, 8]. As can be seen from the collector characteristic in Fig. 2, the HBT exhibits a high collector current density of  $I_C = 1.9 \times 10^5 \text{ A/cm}^2$ . The high collector current at low base-emitter biases demonstrates the excellent low voltage operation of these devices. Relatively large breakdown voltages ( $V_{CE,bkdn} > 2.5$  V) at low currents have been measured.

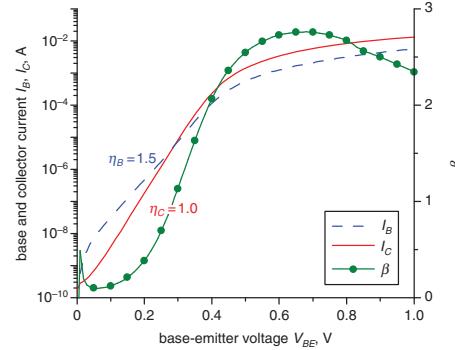


Fig. 1 Gummel plot of  $2 \times 10 \mu\text{m}^2$  HBT showing base current ( $I_B$ ), collector current ( $I_C$ ), and current gain ( $\beta$ )

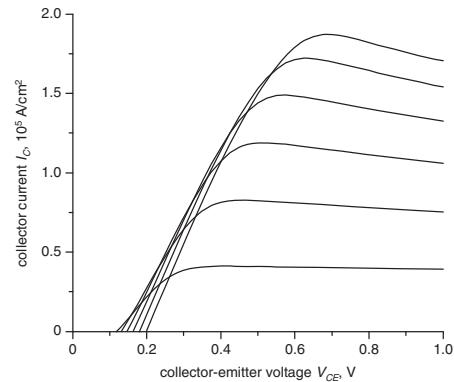


Fig. 2 Common-emitter collector characteristics of  $2 \times 10 \mu\text{m}^2$  HBT  
Base current ( $I_B$ ) stepped from 0 to 12 mA with 2 mA steps

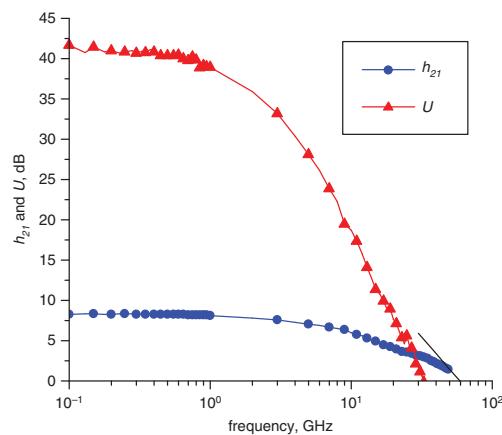
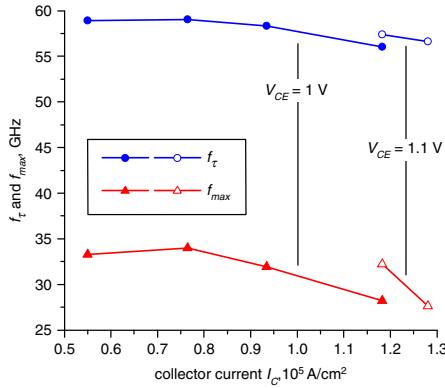


Fig. 3 Plot of short-circuit current gain ( $h_{21}$ ) and Mason's unilateral gain ( $U$ ) at  $V_{CE} = 1$  V and  $I_C = 7.6 \times 10^4 \text{ A/cm}^2$

The measured short-circuit current gain ( $h_{21}$ ) and Mason's unilateral gain ( $U$ ) for  $V_{CE} = 1$  V and  $I_C = 7.6 \times 10^4 \text{ A/cm}^2$  are shown in Fig. 3. The maximum measured short-circuit current gain cutoff frequency was  $f_T = 59$  GHz with an associated maximum frequency of oscillation of  $f_{max} = 34$  GHz ( $V_{CE} = 1$  V,  $I_C = 7.6 \times 10^4 \text{ A/cm}^2$ ; Fig. 4).  $f_{max}$  in

these devices is limited by the device geometry (base-emitter contact spacing of  $\sim 1 \mu\text{m}$ , base contact width of  $2 \mu\text{m}$ , collector thickness of  $1550 \text{ \AA}$ ) resulting in an estimated base resistance of  $R_B = 12.3 \Omega$ , base-collector capacitance of  $C_{BC} = 148.5 \text{ fF}$ , and an associated  $f_{max}/f_\tau$  ratio of 0.61 (with  $f_\tau = 59 \text{ GHz}$ ), very close to the measured ratio of  $f_{max}/f_\tau = 0.57$ .  $f_{max}$  is expected to improve by nearly a factor of 2.5 simply through proper device scaling. Additionally, a selective etch for the emitter mesa definition would facilitate the use of a thinner base [8], which should improve  $f_\tau$ .



**Fig. 4** Plot of short-circuit current cutoff frequency ( $f_\tau$ ) and maximum frequency of oscillation ( $f_{max}$ ) against collector current ( $I_C$ ) and collector-emitter voltage ( $V_{CE}$ )

**Conclusions:**  $\text{In}_{0.59}\text{Al}_{0.31}\text{As}_{0.41}\text{Sb}_{0.59}/\text{In}_{0.27}\text{Ga}_{0.73}\text{Sb}$  double-heterojunction bipolar transistors incorporating  $\text{InAs}_{0.66}\text{Sb}_{0.34}$  in the emitter contact and sub-collector layers have been demonstrated. These HBTs show excellent DC performance and RF performance with a high collector current density ( $I_C = 1.9 \times 10^5 \text{ A/cm}^2$ ), relatively large breakdown voltage ( $V_{CE,bkdn} > 2.5 \text{ V}$ ), a maximum  $f_\tau = 59 \text{ GHz}$  (the highest measured for this material system), and  $f_{max} = 34 \text{ GHz}$ .

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One or more of the Figures in this Letter are available in colour online.

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## References

- 1 Bennett, B.R., Magno, R., Boos, J.B., Kruppa, W., and Ancona, M.G.: ‘Antimonide-based compound semiconductors for electronic devices: a review’, *Solid-State Electron.*, 2005, **49**, pp. 1875–1895
- 2 Papanicolaou, N.A., Bennett, B.R., Boos, J.B., Park, D., and Bass, R.: ‘Sb-based HEMTs with InAlSb/InAs heterojunction’, *Electron. Lett.*, 2005, **41**, pp. 1088–1089
- 3 Deal, W.R., Tsai, R., Lange, M.D., Boos, J.B., Bennett, B.R., and Gutierrez, A.: ‘A W-band InAs/AlSb low-noise/low-power amplifier’, *IEEE Microw. Wirel. Compon. Lett.*, 2005, **15**, pp. 208–210
- 4 Champlain, J.G., Magno, R., Doewon, P., Newman, H.S., and Boos, J.B.: ‘6.2 A Sb-based pN diodes for high frequency applications’. 2007 Joint 32nd Int. Conf. on Infrared and Millimeter Waves and the 15th Int. Conf. on Terahertz Electronics (IRMMW-THz), 2008, pp. 855–856
- 5 Magno, R., Boos, J.B., Campbell, P.M., Bennett, B.R., Glaser, E.R., Tinkham, B.P., Ancona, M.G., Hobart, K.D., Park, D., and Papanicolaou, N.A.: ‘InAlAsSb/InGaSb double heterojunction bipolar transistor’, *Electron. Lett.*, 2005, **41**, pp. 370–371
- 6 Champlain, J.G., Magno, R., and Boos, J.B.: ‘Low resistance, unannealed ohmic contacts to n-type  $\text{InAs}_{0.66}\text{Sb}_{0.34}$ ’, *Electron. Lett.*, 2007, **43**, pp. 1315–1317
- 7 Champlain, J.G., Magno, R., and Boos, J.B.: ‘Low resistance, unannealed, ohmic contacts to p-type  $\text{In}_{0.27}/\text{Ga}_{0.73}/\text{Sb}$ ’, *J. Vac. Sci. Technol. B, Microelectron. Nanometer Struct.*, 2006, **24**, pp. 2388–2390
- 8 Mairiaux, E., Desplanque, L., Wallart, X., and Zaknoune, M.: ‘Microwave performance of InAlAsSb/In<sub>0.35</sub>/Ga<sub>0.65</sub>/Sb/InAlAsSb double heterojunction bipolar transistors’, *IEEE Electron Device Lett.*, 2010, **31**, pp. 299–301